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APPLICATION NO.	FIL	ING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO.
09/073,494 05/06/1998		PAI-HUNG PAN	2915.1US(96-	9834	
	7590	10/24/2002			
JOSEPH A	WALKO	WSKI	EXAM	EXAMINER	
TRASK BRI PO BOX 255	0		VU, HUNG K		
SALT LAKE CITY, UT 84110				ART UNIT	PAPER NUMBER
				2811	

DATE MAILED: 10/24/2002

Please find below and/or attached an Office communication concerning this application or proceeding.

		Application No.	Applicant(s)			
		09/073,494	PAN ET AL.			
	Office Action Summary	Examiner	Art Unit			
		Hung K. Vu	2811			
	The MAILING DATE of this communication app		- · · · ·			
Period fo						
THE N - Exter after: - If the - If NO - Failur - Any re	ORTENED STATUTORY PERIOD FOR REPLY MAILING DATE OF THIS COMMUNICATION. Issions of time may be available under the provisions of 37 CFR 1.13 SIX (6) MONTHS from the mailing date of this communication. period for reply specified above is less than thirty (30) days, a reply period for reply is specified above, the maximum statutory period wire to reply within the set or extended period for reply will, by statute, eply received by the Office later than three months after the mailing of the property of the property of the mailing of the property of the property of the mailing of the property of the prope	6(a). In no event, however, may a reply be tim within the statutory minimum of thirty (30) days ill apply and will expire SIX (6) MONTHS from	nely filed s will be considered timely. the mailing date of this communication.			
1)🖂	Responsive to communication(s) filed on <u>02 A</u>	<u>pril 2002</u> .				
2a) <u></u> □	This action is FINAL . 2b)⊠ This	s action is non-final.				
3) Since this application is in condition for allowance except for formal matters, prosecution as to the ments is closed in accordance with the practice under <i>Ex parte Quayle</i> , 1935 C.D. 11, 453 O.G. 213. Disposition of Claims						
4) 🖂	Claim(s) 23-33 is/are pending in the application	1.				
4	a) Of the above claim(s) is/are withdraw	n from consideration.				
5)	Claim(s) is/are allowed.					
6)🖂	Claim(s) <u>23-33</u> is/are rejected.					
7)	Claim(s) is/are objected to.					
8) 🗌 (Claim(s) are subject to restriction and/or	election requirement.				
Application Papers						
9)∐ T	he specification is objected to by the Examiner.					
10)☐ The drawing(s) filed on is/are: a)☐ accepted or b)☐ objected to by the Examiner.						
Applicant may not request that any objection to the drawing(s) be held in abeyance. See 37 CFR 1.85(a).						
11) ☐ The proposed drawing correction filed on is: a) ☐ approved b) ☐ disapproved by the Examiner.						
If approved, corrected drawings are required in reply to this Office action.						
12)☐ The oath or declaration is objected to by the Examiner.						
Priority u	nder 35 U.S.C. §§ 119 and 120					
13) Acknowledgment is made of a claim for foreign priority under 35 U.S.C. § 119(a)-(d) or (f).						
a) <u></u>	All b) Some * c) None of:					
1	Certified copies of the priority documents	have been received.				
2	2. Certified copies of the priority documents	have been received in Application	on No			
3. Copies of the certified copies of the priority documents have been received in this National Stage application from the International Bureau (PCT Rule 17.2(a)).						
* See the attached detailed Office action for a list of the certified copies not received.						
	14) Acknowledgment is made of a claim for domestic priority under 35 U.S.C. § 119(e) (to a provisional application).					
a) ☐ The translation of the foreign language provisional application has been received. 15)☐ Acknowledgment is made of a claim for domestic priority under 35 U.S.C. §§ 120 and/or 121.						
Attachment(
2) 🔲 Notice	of References Cited (PTO-892) of Draftsperson's Patent Drawing Review (PTO-948) ation Disclosure Statement(s) (PTO-1449) Paper No(s) <u>25</u> .		(PTO-413) Paper No(s) atent Application (PTO-152)			
6. Patent and Trac		on Summery	Ded of D			

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DETAILED ACTION

1. Applicants' communication filed 02/04/02 has been carefully considered by the examiner. The arguments advanced therein are persuasive with respect to the rejections of record, and those rejections are accordingly withdrawn. In view of a further search, however, a new rejection is set forth further below. This action is not made final.

Claim Objections

2. Claim 30 is objected to because of the following informalities: In claim 30, line 5, "a non-crystalline" should be changed to "said non-crystalline" for clarity. Appropriate correction is required.

Claim Rejections - 35 USC § 102

3. The following is a quotation of the appropriate paragraphs of 35 U.S.C. 102 that form the basis for the rejections under this section made in this Office action:

A person shall be entitled to a patent unless -

(e) the invention was described in a patent granted on an application for patent by another filed in the United States before the invention thereof by the applicant for patent, or on an international application by another who has fulfilled the requirements of paragraphs (1), (2), and (4) of section 371(c) of this title before the invention thereof by the applicant for patent.

The changes made to 35 U.S.C. 102(e) by the American Inventors Protection Act of 1999 (AIPA) do not apply to the examination of this application as the application being examined was not (1) filed on or after November 29, 2000, or (2) voluntarily published under 35 U.S.C.

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122(b). Therefore, this application is examined under 35 U.S.C. 102(e) prior to the amendment by the AIPA (pre-AIPA 35 U.S.C. 102(e)).

Claims 23-33 are rejected under 35 U.S.C. 102(e) as being anticipated by Chen et al. (PN 5,472,896). Note Col. 4, lines 23-50 and Figures 1e and 3f of Chen et al..

With regard to claim 23, Chen et al. discloses an operable gate stack, including a non-crystalline metallic silicide film (16).

With regard to claim 24, Chen et al. discloses an operable gate stack, including an amorphous metallic silicide film (16) wherein the metallic silicide film is substantially devoid of silicon clusters. Note that because the metallic silicide film is in amorphous state, it is inherent that it is substantially devoid of silicon clusters.

With regard to claim 25, Chen et al. discloses an operable gate stack on a silicon substrate (10) having a dielectric layer (12) thereover comprising,

- a polysilicon layer (14) disposed over the dielectric layer;
- a non-crystalline metallic silicide film (16) disposed over the polysilicon layer;
- a dielectric cap (22) on the non-crystalline metallic silicide film.

With regard to claim 26, Chen et al. discloses a gate stack structure comprising an operable gate stack on a dielectric layer (12), over a silicon substrate (10), wherein the dielectric layer is substantially devoid of pitting. Note that because a metallic silicide film (16) is in amorphous state, it is inherent that the dielectric layer is substantially devoid of pitting.

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With regard to claim 27, Chen et al. discloses the operable gate stack includes a non-crystalline metallic silicide film (16).

With regard to claim 28, Chen et al. discloses the operable gate stack includes an amorphous metallic silicide film (16) substantially devoid of silicon clusters. Note that because the metallic silicide film is in amorphous state, it is inherent that it is substantially devoid of silicon clusters.

With regard to claim 29, Chen et al. discloses a semiconductor device comprising at least one gate stack having a non-crystalline metallic silicide film (16).

With regard to claim 30, Chen et al. discloses the at least one gate stack comprising,

a silicon substrate (10) having a dielectric layer (12) thereover;

a polysilicon layer (14) disposed over the dielectric layer;

the non-crystalline metallic silicide film (16) disposed over the polysilicon layer;

a dielectric cap (22) on the non-crystalline metallic silicide film.

With regard to claim 31, Chen et al. discloses a semiconductor device comprising at least one gate stack structure on a dielectric layer (12), over a silicon substrate (10), wherein the dielectric layer is substantially devoid of pitting. Note that because a metallic silicide film (16) is in amorphous state, it is inherent that the dielectric layer is substantially devoid of pitting.

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With regard to claim 32, Chen et al. discloses the at least one gate stack structure includes a non-crystalline metallic silicide film (16).

With regard to claim 33, Chen et al. discloses the at least one gate stack structure includes an amorphous silicide film (16) substantially devoid of silicon clusters. Note that because the metallic silicide film is in amorphous state, it is inherent that it is substantially devoid of silicon clusters.

Response to Arguments

4. Applicant's arguments with respect to claims 23-33 have been considered but are moot in view of the new ground(s) of rejection.

Conclusion

5. Any inquiry concerning this communication or earlier communications from the examiner should be directed to Hung K. Vu whose telephone number is (703) 308-4079. The examiner can normally be reached on Mon-Thurs 7:00-5:30, Eastern Time.

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Tom Thomas can be reached on (703) 308-2772. The fax phone numbers for the organization where this application or proceeding is assigned are (703) 308-7722 for regular communications and (703) 308-7722 for After Final communications.

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Any inquiry of a general nature or relating to the status of this application or proceeding should be directed to the receptionist whose telephone number is (703) 308-0956.

Vu

October 18, 2002

TOM THOMAS
SUPERVISORY PATENT EXAMINER
TECHNOLOGY GENTER 2800